

## High Energy Small Focus Electron Sources

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## EH-20

This electron source delivers a high power density beam into a small spot, for applications including evaporation, X-ray generation, thermal shocks, annealing, and detector testing.

### Key features

- Energy range 1 keV to 20 keV
- Beam size (min.) <150  $\mu\text{m}$  at low current and 150 mm WD and max. energy

Versions	EH-20-2	EH-20-10	EH-20-20
Beam current max.	100 $\mu\text{A}$	0.5 mA	1.0 mA



Not all parameters can be reached simultaneously. Above specifications may change without notice. Pictures / diagrams for reference only.

### Characteristics

- Working distance 150 mm – 750 mm
- Basic beam blanking (optional)
- Beam blanking, external (optional)
- Beam pulsing (optional)
- Differential pumping (DP) (optional)
- Advanced beam steering (patented)
- Parallel beam shift (optional)
- Computer control (optional)
- Magnetic shielding (optional)
- Beam scanning (optional)

- › Low Energy Electron Sources
- › Electron Sources for RHEED
- › Accessories for Electron Sources
- › Ion Sources
- › X-ray Source
- › Energy Analyzers & Imaging Energy Filters
- › Charged Particle Detectors
- › PEEM & IEEM
- › UHV-Systems for Surface Analysis
- › Packages for Surface Analysis
- › Data Acquisition & Instrument Control Software
- [Microprocessor controlled beam current regulation \(optional\)](#)
- Remote control

## Typical Applications

- [Electron beam treatment](#)
- [Detector testing](#)
- [Evaporation](#)
- [Annealing](#)
- [Desorption](#)
- [Dissociation](#)
- [Ionization of gases](#)
- [Cathodoluminescence](#)
- [X-ray emission analyses](#)
- [X-ray generation](#)

## Related Products

- [Filaments](#)
- [Pre-mounted, pre-aligned cathode units](#)
- [Complete service kit](#)
- [Diagnostic box](#)
- [Magnetic shielding for the beam path](#)
- [X-ray shielding glass covers](#)
- [Fluorescent screens](#)
- [Scan amplifier](#)
- [Faraday cups](#)
- [Sample current measurement kit](#)
- [Gun control module](#)

## PRODUCTS

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## APPLICATIONS

- › [In situ Characterization](#)
- › [Surface Analysis Techniques](#)
- › [Material Growth Monitoring](#)
- › [Electron Diffraction](#)
- › [Scanning Electron Microscopy](#)
- › [Photoelectron Microscopy \(PEEM\)](#)
- › [Depth Profiling](#)
- › [Space Environment Simulation](#)
- › [Surface & Materials Modification](#)

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